

# TRANSMITTAL FORM

JC474 U.S. PTO  
09/683088  
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Electronic Version 1.0.2

Stylesheet Version: 1.0

Attorney Docket Number: BUR920000077

## SINGLE REACTOR, MULTI-PRESSURE CHEMICAL VAPOR DEPOSITION FOR SEMICONDUCTOR DEVICES

First Named Inventor: Jack Chu

### SUBMITTED BY

Name:

Mr. Robert A. Walsh Esq.

Registration Number:

26,516

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Walsh /s/

Date Signed: 20011116

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### Attached Files:

bibd-transmittal

BUR920000077US1apds.xml

fee-transmittal

BUR920000077US1fee.xml

patent-assignment

BUR920000077US1asgn.xml

specification

BUR920000077US1.xml

declaration

BUR920000077 Dec. 1.tif

declaration  
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BUR920000077 Dec. 2.tif  
BUR920000077 Dec. 3.tif  
BUR920000077 Dec. 4.tif  
BUR920000077 Dec. 5.tif  
BUR920000077 Dec. 6.tif

Attached Image File(s):

BUR920000077 Dec. 1.tif  
BUR920000077 Dec. 2.tif  
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BUR920000077 Dec. 4.tif  
BUR920000077 Dec. 5.tif  
BUR920000077 Dec. 6.tif

09683088

Comments:

ASSIGNEE: INTERNATIONAL BUSINESS MACHINES CORPORATION ASSIGNEE ADDRESS: ARMONK, NY  
10504

09683088.11.16.1

# FEE TRANSMITTAL

Electronic Version 1.1.0

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*Patent fees are subject to annual revisions on or about October 1st of each year.*

Large Entity

**TOTAL FEES AUTHORIZED: \$ 780**

The commissioner is hereby authorized to charge indicated processing and/or publication fees and credit any overpayments to:

Deposit Account Number: 09-0456



Deposit Account Name: International Business Machines Corporation

Charge Any Additional Fee Required Under 37 C.F.R. Sections 1.16 and 1.17.

## SUBMITTED BY

Authorized Name:

Robert A. Walsh

Electronic Signature Mark:

Robert A. Walsh /s/

Date Signed:

20011115

## BASIC FILING FEE

Fee Description	Fee Code	Fee Paid
Utility Filing Fee	101	\$ 740

Subtotal For Basic Filing Fee: \$ 740

## EXTRA CLAIM FEES

	Fee Code	Fee	Extra Claims	Fee Paid
Total Claims: 20	103	\$ 18	0	\$ 0
Independent Claims: 2	102	\$ 84	0	\$ 0

Subtotal For Extra Claims Fees: \$ 0

ADDITIONAL FEES

Fee Description	Fee Code	Fee Paid
Recording Each Patent Assignment Per Property Fee	581	\$ 40

Subtotal For Additional Fees: \$ 40

09683088 - 11.15.11

Electronic Filing System (EFS) Data  
Electronic Patent Application Submission  
USPTO Use Only

EFS ID: 12989

Application ID: 09683088

Title of Invention: SINGLE REACTOR, MULTI-  
PRESSURE CHEMICAL VAPOR  
DEPOSITION FOR  
SEMICONDUCTOR DEVICES

First Named Inventor: Jack Chu

Domestic/Foreign Application: Domestic Application

Filing Date: null

Effective Receipt Date: 2001-11-16



Submission Type: Utility Patent Filing

Filing Type: new-utility

Confirmation Number: 0

Attorney Docket Number: BUR920000077

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